



Image

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 9126**
Akira FUKUNAGA et al. : Docket No. 2001-1724A
Serial No. 09/988,719 : Group Art Unit 1763
Filed November 20, 2001 : Examiner R. Culbert
METHOD AND APPARATUS FOR :
ETCHING RUTHENIUM FILMS

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of November 19, 2003, Applicant hereby elects the invention of Group I, claims 1-8, drawn to a method of etching, without traverse, for further prosecution. In view of this election, a full examination on the merits of the present application is respectfully requested.

Respectfully submitted,

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December 2, 2003